

Literature Resource Form

KRI REFERENCE #	TITLE	PUBLICATION	PAGES	SEND .pdf
Technical & Application Notes:				
1	Broad-Beam Industrial Ion Sources	Technical Note KRI-01	2	
2	Ion-Beam Neutralization	Technical Note KRI-02	2	
3	Charge and Momentum Exchange in an Ion Beam	Technical Note KRI-03	2	
4	Gas Cleanliness	Technical Note KRI-04	2	
5	Ion-Assist Doses	Technical Note KRI-05	2	
6	In-Situ Cleaning for Thin Film Deposition	Technical Note KRI-06	2	
7	Ion Source or Plasma	Technical Note KRI-07	2	
8	Cleaning/Activation of Polymer Surfaces	Technical Note KRI-08	2	
9	Effects of Target Temperature	Technical Note KRI-09	4	
10	Possible Target Contamination When Using an End-Hall Ion Source	Technical Note KRI-10	4	
11	Shift-Free Optical Coating	Application Note AN-01	3	
12	End-Hall Processing with a Nonplanetary Rotating Stage	Technical Report TR-01	8	
Books:				
100	Applications of Broad-Beam Ion Sources: An Introduction	Harold Kaufman & KRI		
101	Operation of Broad-Beam Sources	Harold Kaufman & KRI		
Articles:				
30	Biased Target Deposition	J.Vac.Sci. Technol A18(1), Jan/Feb 2000	5	
31	Magnetron as Cathode - Neutralizer for Ion Source in Ion-Assisted Operation	2003 SVC Technical Conference Proceedings	5	
32	Substrate Heating Using Several Configuration of an End-Hall Ion Source	2003 SVC Technical Conference Proceedings	5	
33	Modular Linear Ion Source	2004 SVC Technical Conference Proceedings	6	
34	Low Energy End Hall Ion Source Characterization at Millitorr Pressures	2005 SVC Technical Conference Proceedings	7	
35	Low Energy Ion Beam Etching	2006 SVC Technical Conference Proceedings	5	
36	Development & Applications of Ion Sources	2007 SVC Technical Conference Proceedings	6	
37	Low-Energy High-Flux Reactive Ion Assisted Deposition of Oxide Optical Coatings: Performance, Durability, Stability, and Scalability	SPIE Proceedings 2262, 1994	12	
38	Ion Doses for Low-Energy, Ion Assist Applications Shop Notes	J.Vac.Sci. Technol A22(1), Jan/Feb 2004	4	
39	Ion-Assist Application of Broad-Beam Ion Sources	SPIE Proceedings 5527, Aug 4, 2004	19	
40	Simultaneous Effects on Topography, Composition, and Texture	James Harper, Dept of Physics, University of New Hampshire	8	
41	End-Hall Ion Source	J.Vac.Sci. Technol A5(4), Jul/Aug 1987	4	
42	The Evolution of R&D in the U.S.	2010 SVC Bulletin TechCon Review	3	
43	Target Temperature and Ar ⁺ Ion Damage Depth	2011 SVC Bulletin TechCon Review	2	
KRI Literature:				
Lit-50	"Gridless Ion & Plasma Sources" (Brochure)	Kaufman & Robinson Inc.	4	
Lit-53	"Gridded Ion Sources" (Brochure)	Kaufman & Robinson Inc.	4	